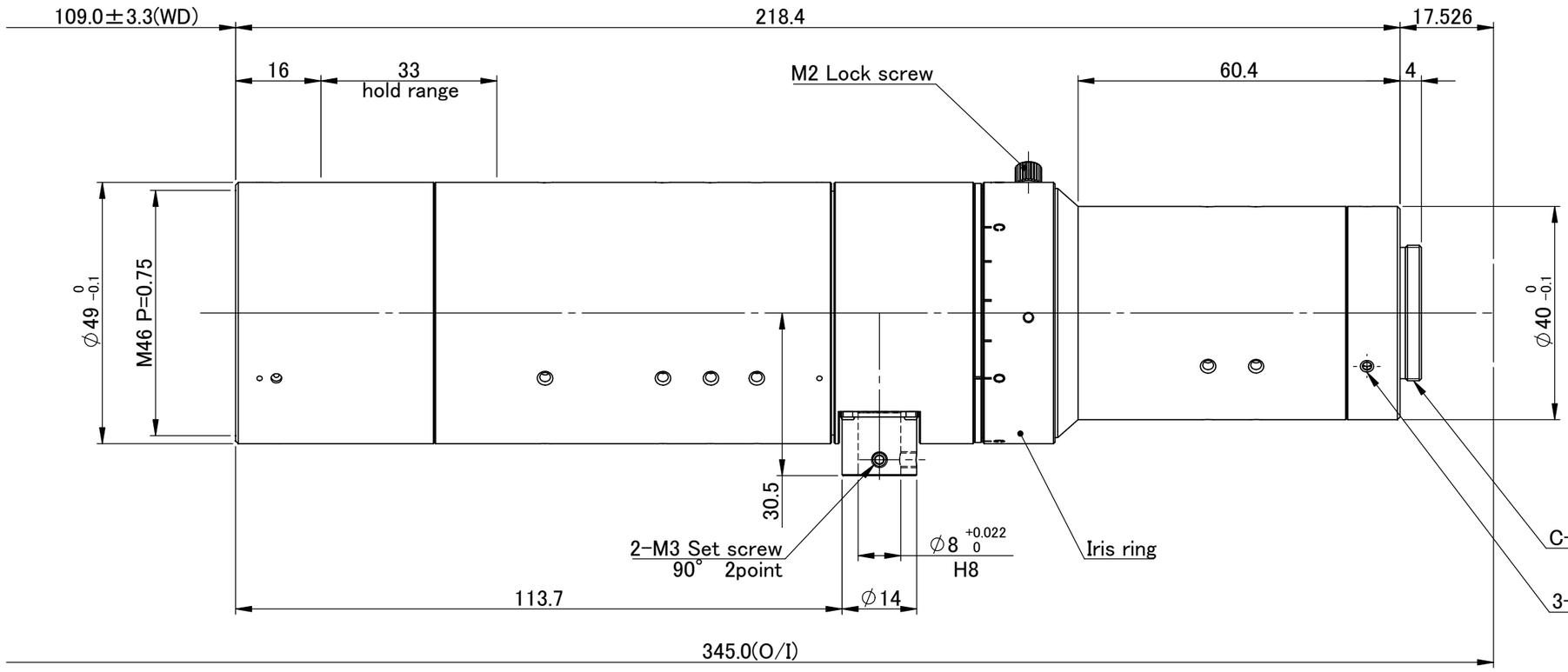
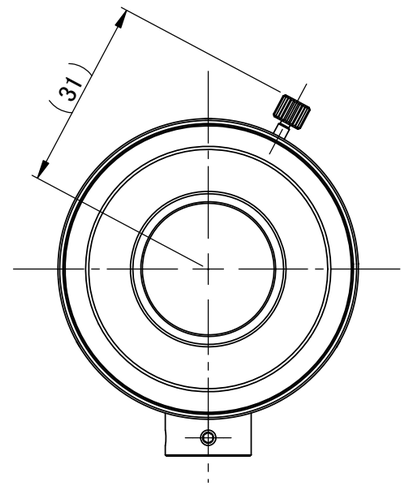
Confidential





TREATMENT 処理		–			MATERIAL	–	UNIT	METHOD			
					CHAMFER	–					
TREATMENT CONTACT 処理接点		–			FINISHING	–	mm				
					DECENTRATION	–					
APPROVED	CHECKED	DESIGNED	DRAWN	TOLERANCE	–	REMARK	VS-TCTV1-110CO/S				
				ANGLE	–	NAME	DRAWING				
鈴木(利)	内川	千嶋	千嶋	SCALE	1:1						
				DATE	2026.03.16	DRAW NO.	M2170D-A00100				

△×			
NO. ×	REVISION	DATE	NAME

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